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PATENT NUMBER and  
ISSUE DATE

## U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS 427 252	SUBCLASS 099	GAU 1751	EXAMINER <i>K. Chen</i>
10007119	10/26/2001				

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\*\*CONTINUING DATA VERIFIED:

\*\* FOREIGN APPLICATIONS VERIFIED:

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed	<input type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO	
35 USC 119 conditions met	<input type="checkbox"/> yes <input type="checkbox"/> no		13249.348
Verified and Acknowledged Examiners's initials			
TITLE : Chemical vapor deposition method of making layered superlattice materials using trimethylbismuth			
U.S. DEPT. OF COMM./PAT. & TM-PTC-435L (Rev. 12-94)			

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	Total Claims Print Claim for O.G.
ISSUE FEE			DRAWING
Amount Due	Date Paid		Sheets Drawn Figs. Drawn Print Fig.
		Primary Examiner	
		PREPARED FOR ISSUE	Application Examiner
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